FORM PTO-1449									rtment of Co nd Tradema		Atty. Doci BUR9200	ket No. 30177US1		Application No. 10/707,905		
Applicant Douglas D. COOLBAUGH, et al.																
NON 38 51	se se						essa	ry)		Filing Dat January 2			Group 2811			
U.S. PATENT DOCUMENTS													· · · · · · · · · · · · · · · · · · ·	<del></del>		
EXAMINE															DATE	
INITIAL		D	DOCUMENT NUMBER						DATE	1	IAME	CLASS	SUE	BCLASS	IF APPROPRIATE	
Sie		6	5	2	1	5	0	6	02/18/03	COOLB	AUGH et a	ı.				
		6	0	1	4	0	6	4	01/11/00	BOLES	et al.					
		4	5	9	0	4	3	9	05/20/86	GOGGI	N					
		3	6	3	8	3	0	0	02/01/72	FOXHA	LL et al.					
		4	6	4	2	5	8	0	02/10/87	SCOTT						
		4	6	6	8	3	0	6	05/26/87	NISHIZ	AWA					
<b></b>		6	5	5	9	0	2	4	05/06/03	BOLES	et al.					
Y		6	5	2	1	9	3	9	02/18/03	YEO et	al. 		_			
		<u> </u>	ļ.,												<u> </u>	
				ļ												
		-	_	_	_		-						<u> </u>		ļ: 	
		-	-	-	_	-					<del></del>					
FOREIGN PATENT DOCUMENTS																
		I							TEIOIT AT		JOHILLATO	· · · · · · · · · · · · · · · · · · ·	<u> </u>		TRANS	ATION
		D	OCI	UME	NT	NUI	MBE	R	DATE	COUNTRY		CLASS	ASS SUBCL		TRANSLATION YES NO	
5AB	6 3	-	3	0	0	5	7	0	12/07/88	JAPAN					Abstract	
SPO	64	-		1	9	7	7	9	01/23/89	JAPAN						Х
				ļ				Ĺ							,	
		0	THE	RD	oc	UMI	ENT	S (I	ncluding Au	thor, Tit	e, Date, Pe	rtinent Pa	iges, E	itc.)		
SKO		1 An Article of VELLANKI et al., entitled: "Highly Conductive n+ Layers in InP:Fe Created by MeV														
		_	Energy Si, S, and Si/S Implantation for Application to Microwave Devices", Journal of Electronic													
			Materials, Vol. 22, No. 1, 1993, pp. 73-80													
· · · · · · · · · · · · · · · · · · ·																
		ļ		····							***********	***************************************	·····	<del> </del>		
EVANAINE		Ļ	Ļ			0	<del></del>			D.4	TE CONO!	DEBED		/	- <i>o</i>	
*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation													n citation			
									e copy of thi						ne unougi	i CitatiOII